1449 (Modified)

**Information Disclosure** Statement By Applicant Atty Docket No. LAM1P182/P1183 Application No.: 10/712,410

Applicant:

Wagganer et al. Filing Date

Group 2818

(Use Several Sheets if Necessary)

November 12, 2003

U.S. Patent Documents

			O.D. I mici	it Documents			
Examiner						Sub-	Filing
Initial	No.	Patent No.	Date	Patentee	Class	class	Date
80	A	5,658,425	08/19/97	Halman et al.	438	620	06/07/95
PD	В	6,080,680	06/27/00	Lee et al.	438	727	12/19/97
PD	C	6,090,304	07/18/00	Zhu et al.	216	79	08/28/97
PO	D	6,518,174B2	02/11/03	Annapragada et al.	438	637	12/22/00
	E						
	F						
	G						
	H						
	I						

Foreign Patent or Published Foreign Patent Application

	•	OLCIGII I MICIN	t of a distinct	. 1 0141611 1 814111	ppeatio			
Examiner		Document	Publication	Country or		Sub-	Trans	slation
Initial	No.	No.	Date	Patent Office	Class	class	Yes	No
	J							
-	K							
	L							
	M							
	N				1			

## Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication			
PD		Calvin T. Gabriel, et al., "Measuring and Minimizing Line Edge Roughness in BEOL Damascene Dielectric Patterning", 2003 AVS 4th Int'l. Conf. on Microelectronics and Interfaces, March 3-6, Santa Clara, CA, pages 204-207.			
	P				
	Q				
Examiner	PH	UCT. DANG Date Considered 1/29/05			

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.